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U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY/NAME	CLASS	SUB CLASS	TRANSLATION YES NO

OTHER DOCUMENTS

Kay.	Article entitled, "Influence of ^{16}O , ^{12}C , ^{14}N , and Noble Gases on the Crystallization of Amorphous Si Layers", published in J. Appl. Phys., Vol. 48, by E. F. Kennedy et al., (1977), pp. 4241-4246
K. N.	Article entitled, "Microstructure of xenon-implanted silicon", published in J. Vac. Sci. Technol., Vol. 12, by S. Mader and K. N. Tu, (1975), pp. 501-503
K. N.	Article entitled, "Influence of Surface Absorption Characteristics on Reactively Sputtered Films Grown in the Biased and Unbiased Modes", by H. F. Winters and E. Kay, published in J. Appl. Phys., Vol. 43, No. 3, March 1972, pp. 794-799